

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Gormley et al.

GROUP:

2822

SERIAL NO:

10/617,427

EXAMINER:.

P.Perkins

FILED:

07/11/03

Confirmation No.:

3233

FOR:

METHOD FOR FORMING A MICRO-MECHANICAL COMPONENT IN A SEMICONDUCTOR WAFER, AND A SEMICONDUCTOR WAFER

COMPRISING A MICRO-MECHANICAL COMPONENT FORMED THEREIN

Mail Stop Amendment **Commissioner of Patents** P.O. Box 1450 Alexandria, VA 22313-1450

Attn: Issue Fee

TRANSMITTAL OF FORMAL DRAWINGS

Applicant submits herewith new drawing(s) for this application. Attached please find four (4) sheets of formal drawings for this application.

Respectfully submitted,

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I hereby certify that this paper (along with any paper referred to as being attached or enclosed) is being deposited with the United States Postal Service on the date shown below with sufficient postage as first class mail in an envelope addressed to the Commissioner of Patents and Trademarks, P.O. Box 1450, Alexandria, VA 22313-1450, Mai